

<b>Notice of References Cited</b>	Application/Control No. 09/840,500	Applicant(s)/Patent Under Reexamination TSAI, ROGER S.	
	Examiner Thomas H. Stevens	Art Unit 2123	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,878,053	03-1999	Koh et al.	714/724
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Pfeifer et al., "Fabrication and Characterization of Freely Positionable Silicon-On-Sapphire Photoconductive Probes" 1994 Optical Society of America pg.2547-2552.
	V	Ishimaru et al., "Mechanical Stress Induced MOSFET Punch-through and Process Optimization for Deep Submicron TEOS-O3 Filled STI Device" 1997 VLSI Symposium pg.123-124.
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.